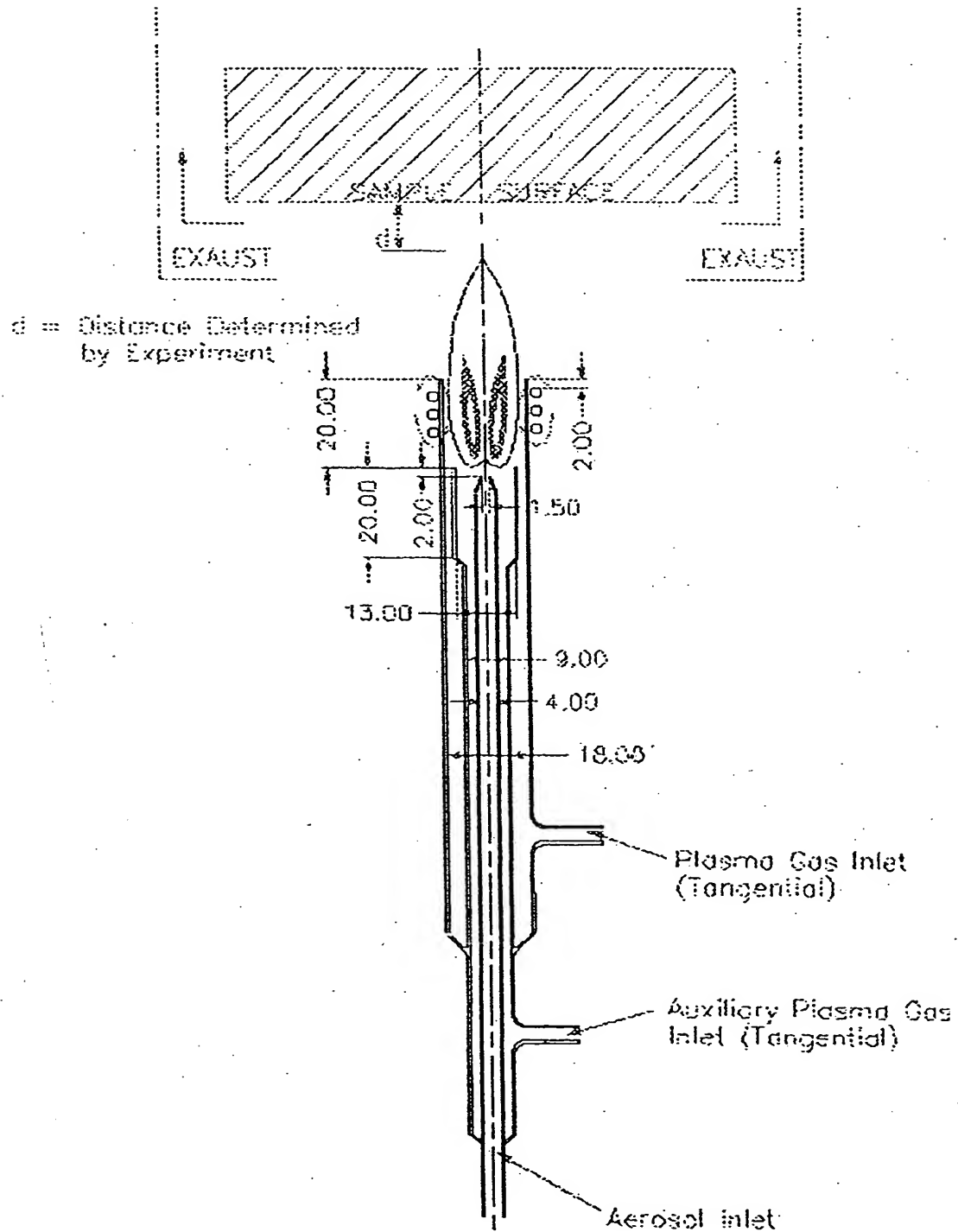
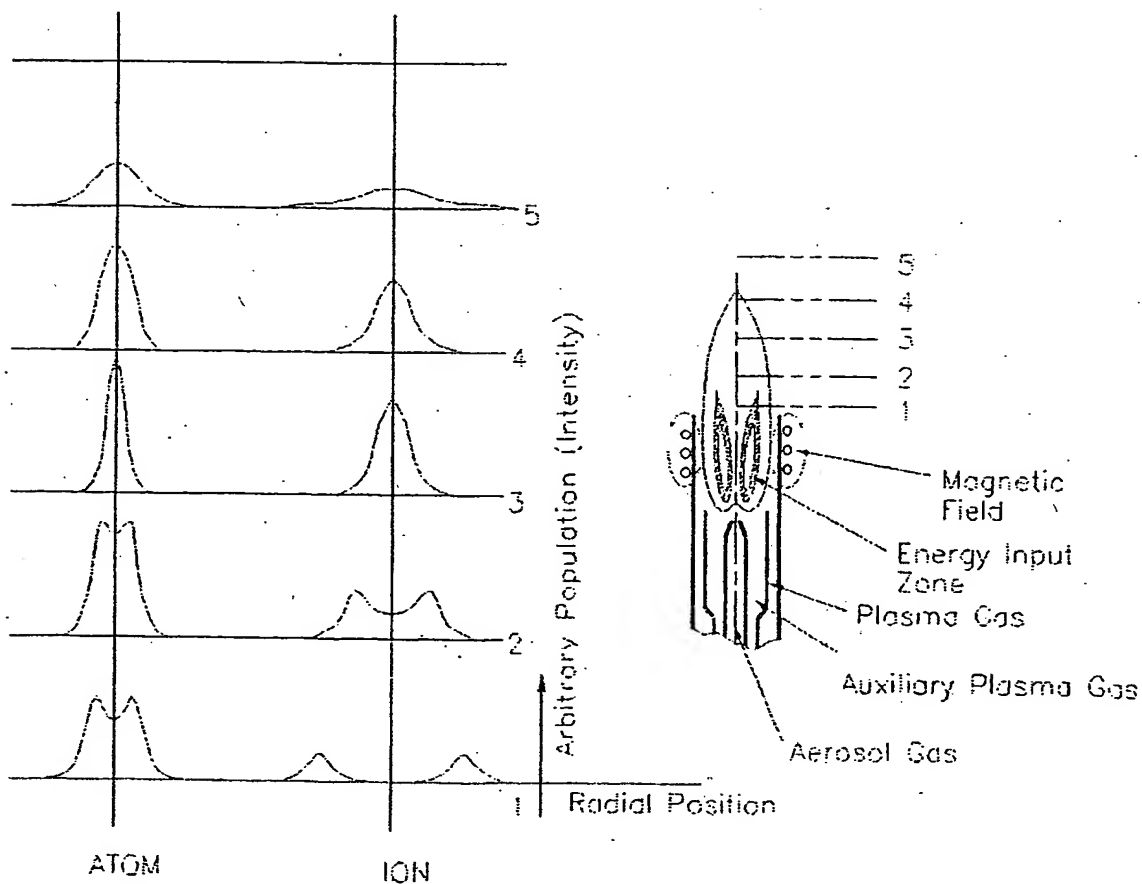


**Fig 1: ICP Torch**



(all measurements are in millimeters)

Fig. 2: Atom and Ion Distribution in the ICP



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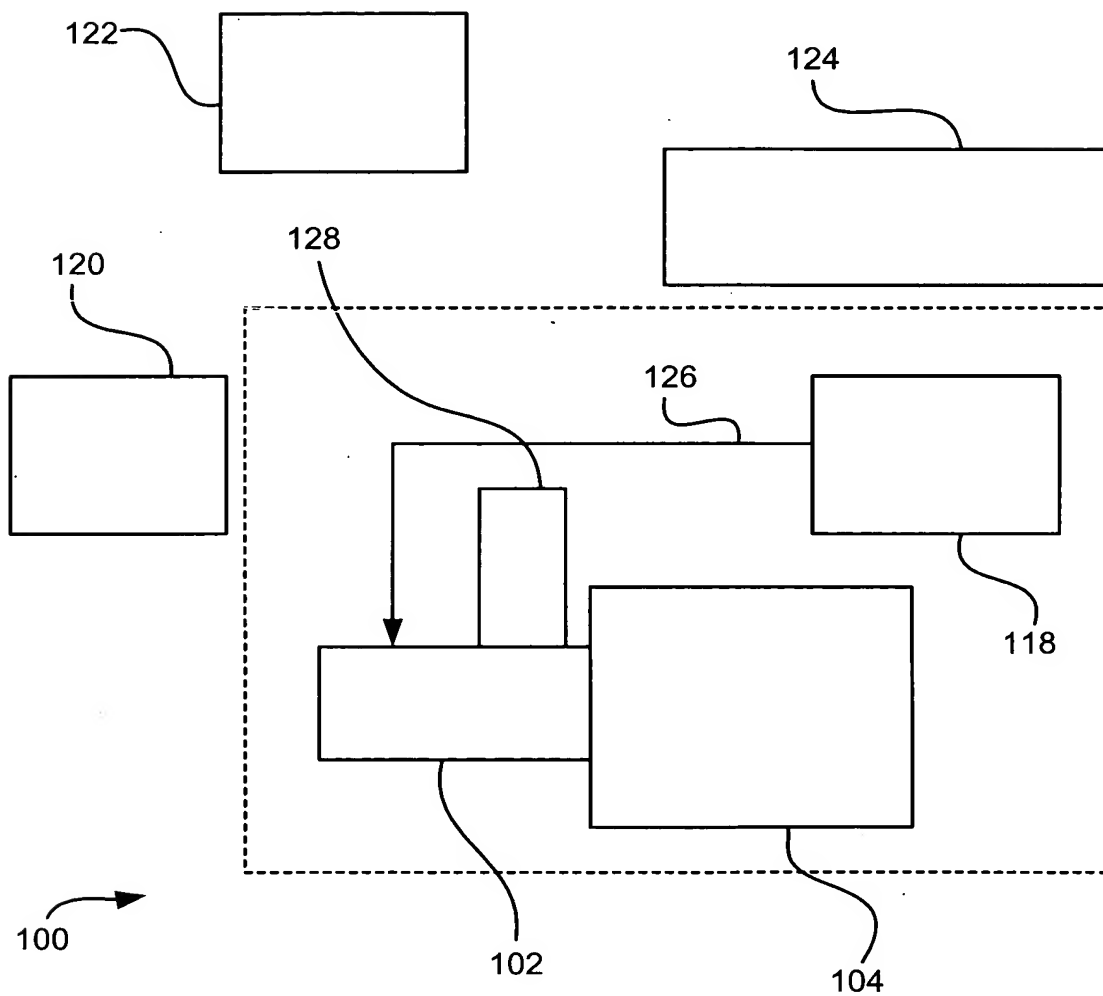
Attorney: Jason D. Lohr

Filed: Herewith

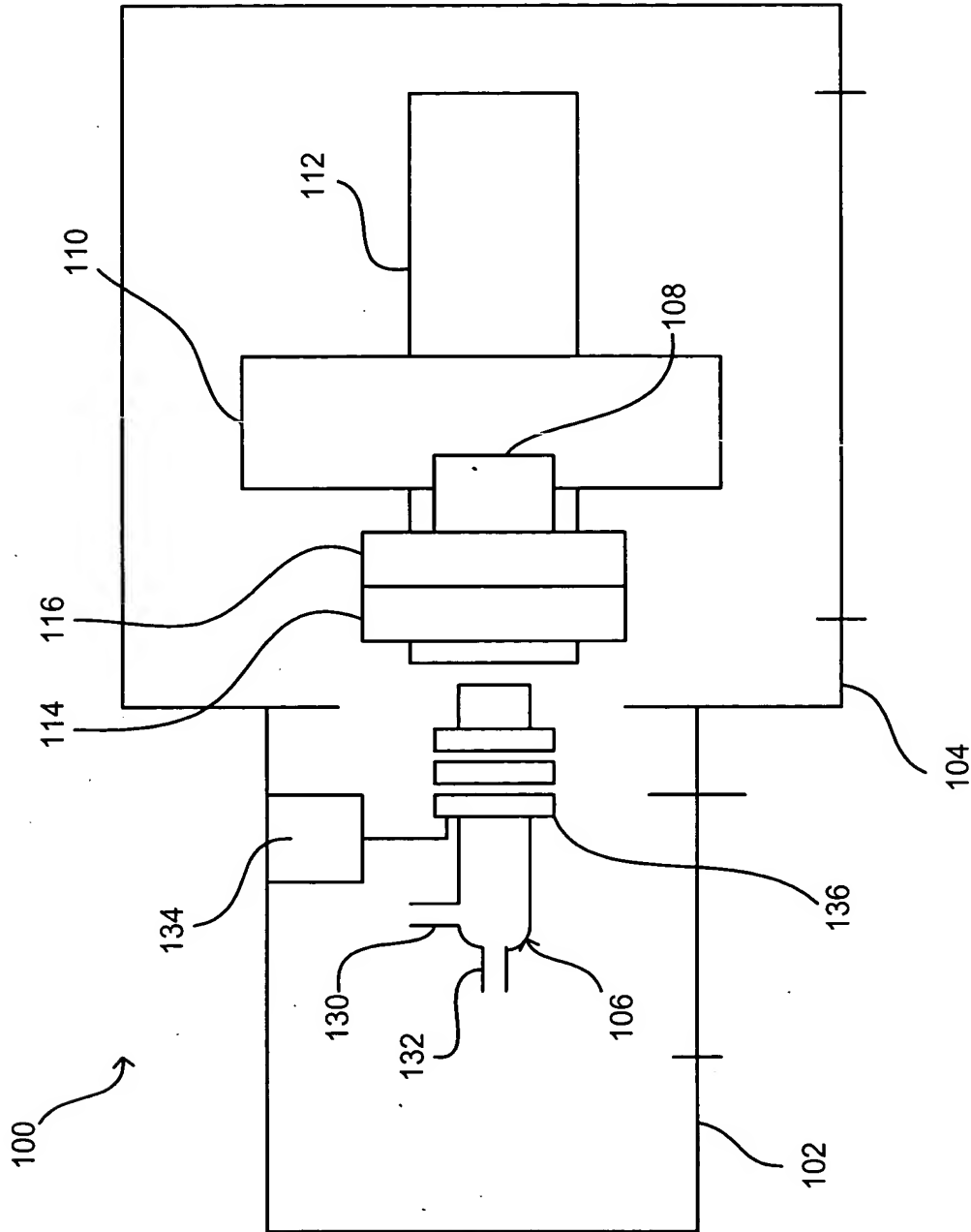
Phone: (415) 362-3800

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**FIG. 3**



**FIG. 4**

THE APPARATUS AND METHOD, FOR ATMOSPHERIC PRESSURE INACTIVE  
ATOM PLASMA PROCESSING FOR SHAPING OF DAMAGED SURFACES

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Applicant(s): Jeffrey W. Carr

Appl. No.: Unknown

Attorney: Jason D. Lohr

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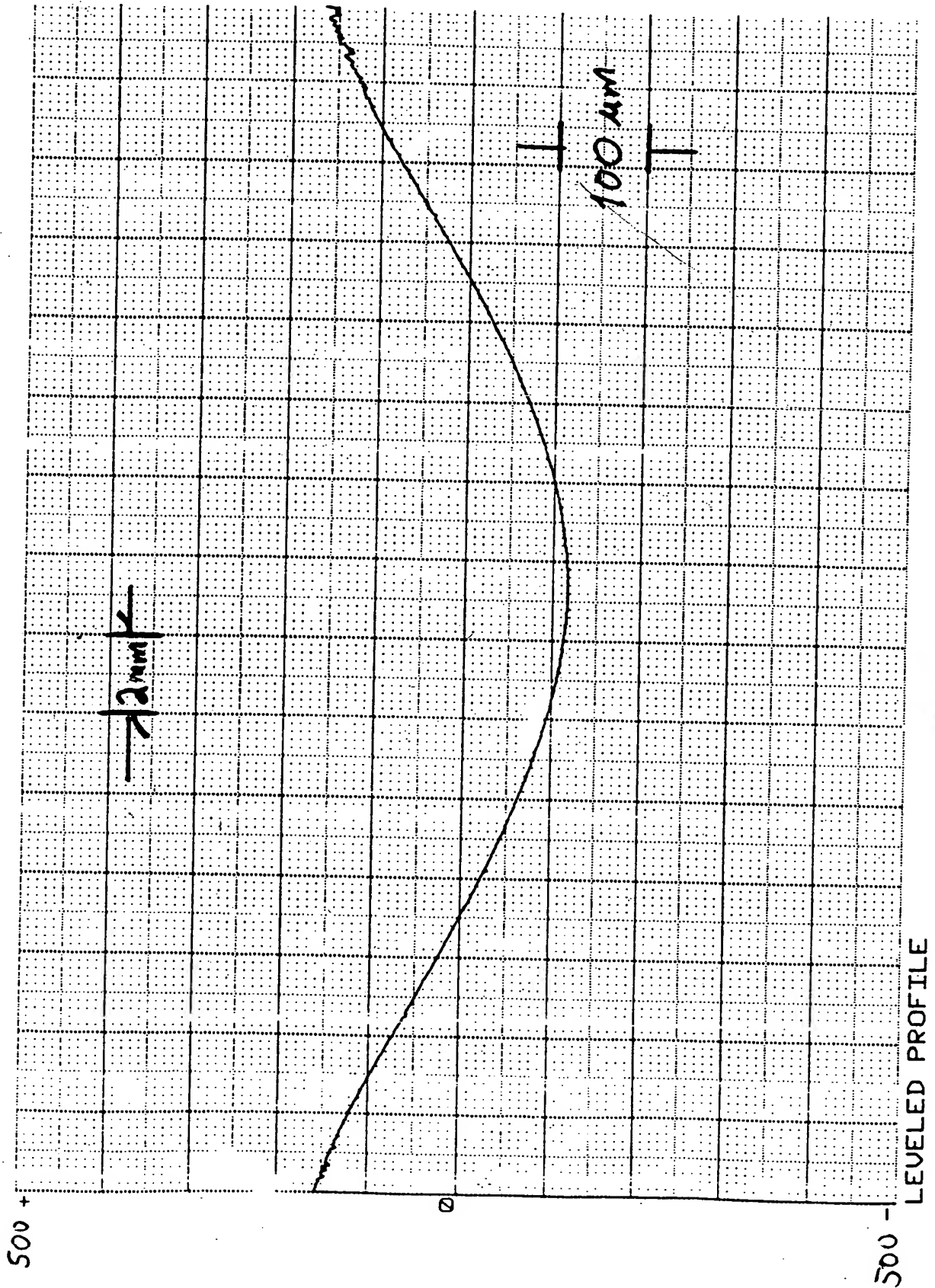


Fig 5

THE APPARATUS AND METHOD FOR ATMOSPHERIC PRESSURE REACTIVE  
ATOM PLASMA PROCESSING FOR SHAPING OF DAMAGED SURFACES

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Appl. No.: Unknown

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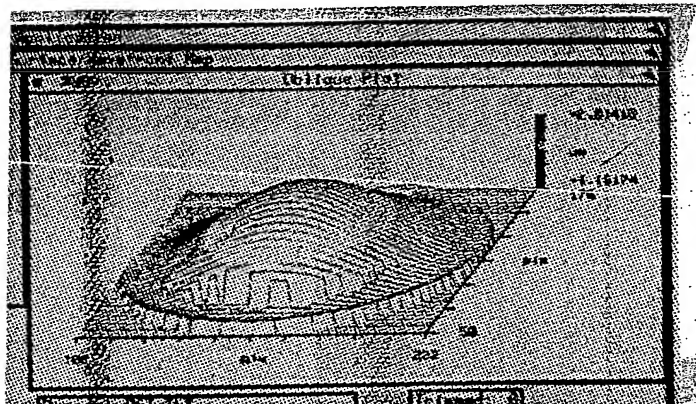
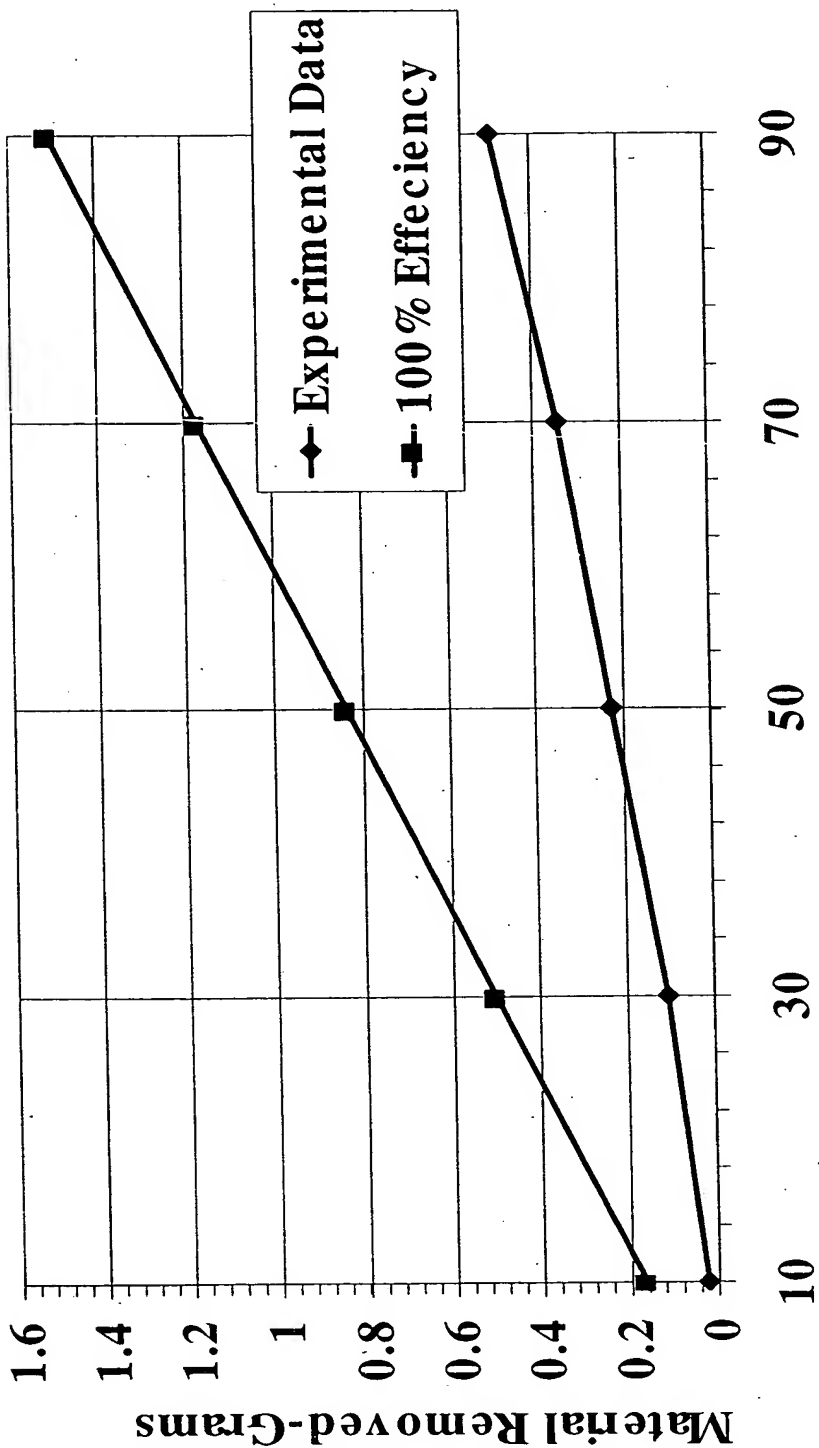


Fig 6

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TOTAL SECRET

# Effect of Reaction Gas Flow Rate on Removal



Reaction Gas Concentration

Fig 7

FOOT SEEDS

# Effect of Distance from Plasma

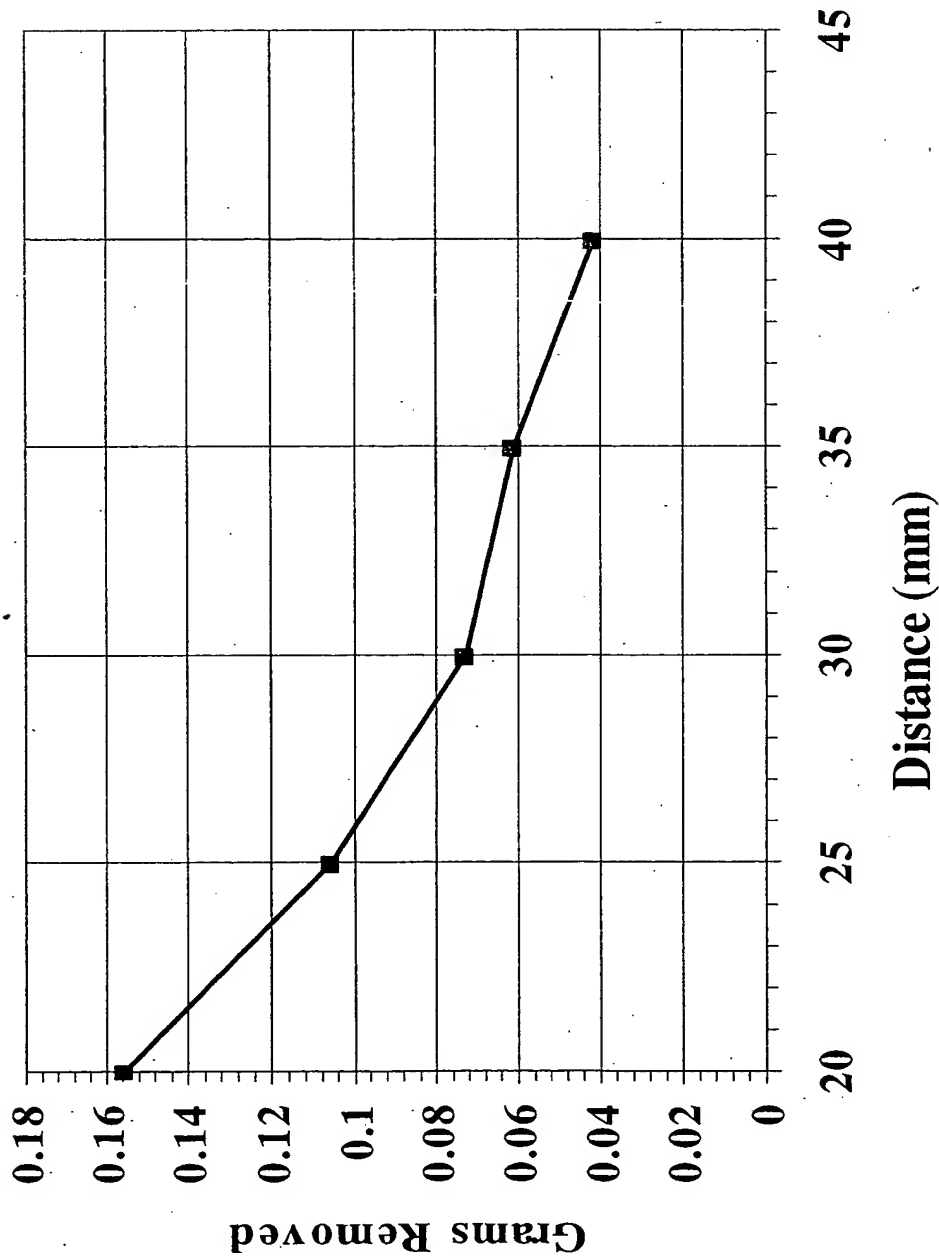


Fig 8



TOTOT" SE22000T

# Effect of Reaction Gas Flow Rate on Efficiency

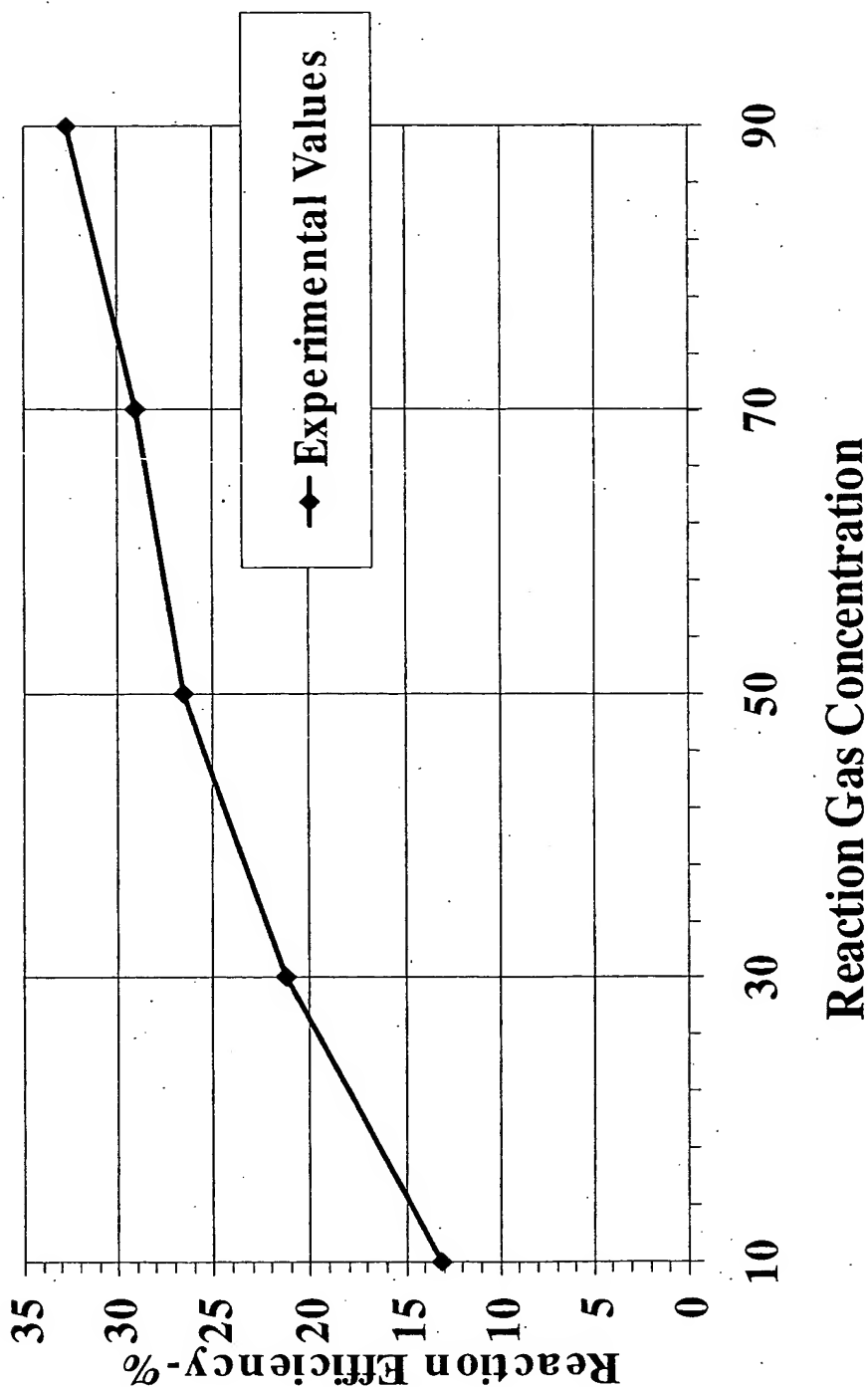


Fig 9

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# Effect of Distance from Plasma on Efficiency

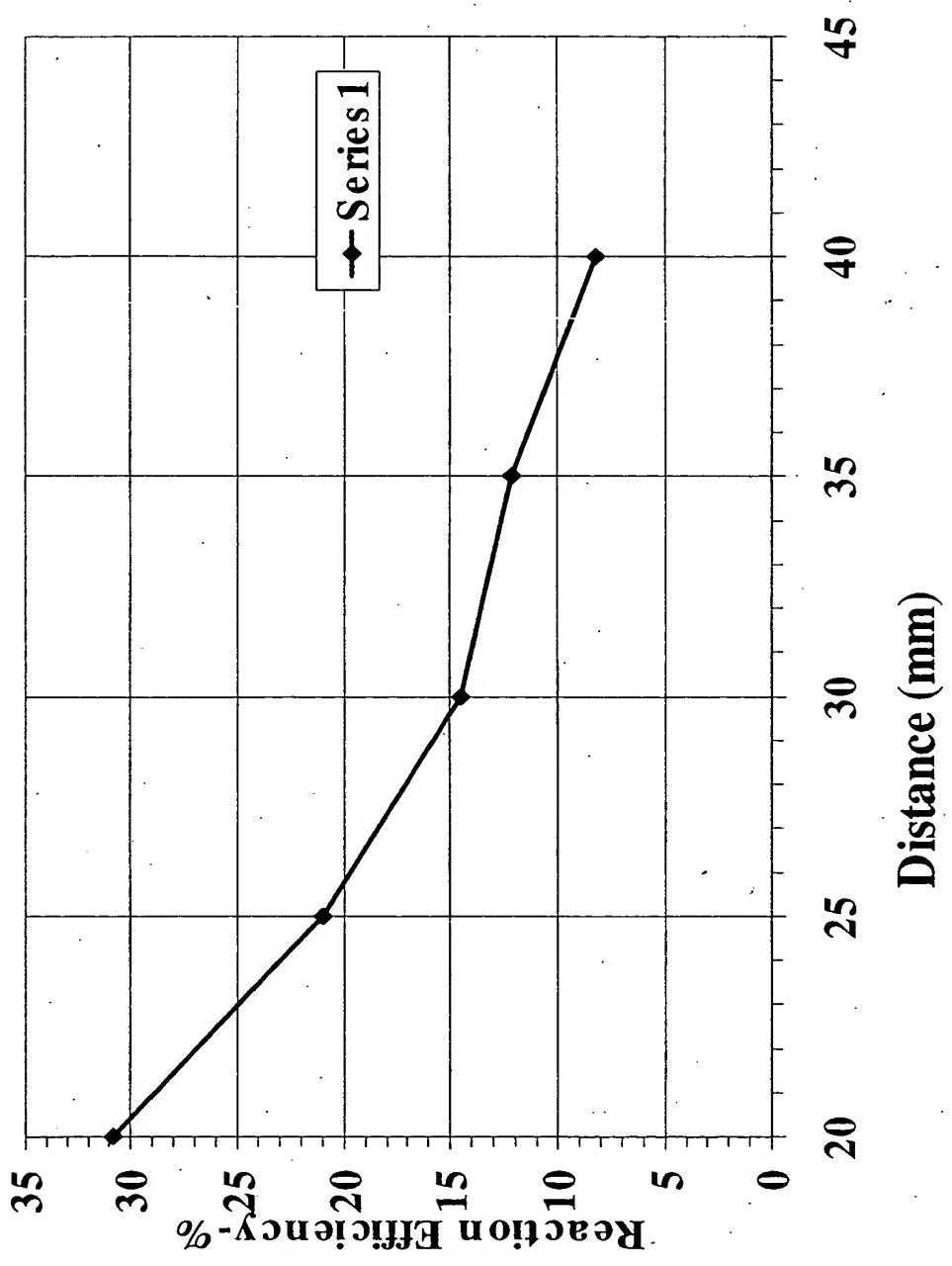


Fig 10